

Form PTO 1449 U.S. Department of Commerce Patent and Trademark Office. Information Disclosure Statement by Applicant	ATTY. DOCKET NUMBER NITT.0161	SERIAL NUMBER To Be Assigned 10/699,853
	APPLICANT Shichi et al	
	FILING DATE Concurrently Herewith	GROUP 2881

U.S. Patent Documents

Examiner Initial	Cited by Examiner in Parent	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE
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CMK	X	"Electron and Ion Beam Handbook", Third Edition, (Japan Society for the Promotion of Science, 132 commission, Nikkan Kogyo ShinbunSha), pp. 458-461
EXAMINER <i>Chris Kalwood</i>		DATE CONSIDERED 04/23/04

EXAMINER: Initial if citation is considered, whether or not citation is in conformance with MPEP 609; draw a line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant